

WHAT IS CLAIMED IS:

1. A substrate processing apparatus comprising :

a chamber having a container and a lid for closing an opening of the container; and

an elevator for moving the lid, disposed integrally with the chamber.

2. A substrate processing apparatus according to claim 1, wherein the opening is provided on top of the container; and

wherein the elevator is disposed on an upper side of the chamber.

3. A substrate processing apparatus according to claim 2, wherein the elevator has:

a first pole erected from an upper side of the container so as to extend vertically;

a driving source, attached to the upper lid, for outputting a predetermined turning force; and

a power converting mechanism for converting the turning force outputted from the driving source into a vertical force for vertically moving the upper lid along the first pole.

4. A substrate processing apparatus according to claim 3, wherein the power converting mechanism includes:

a first tubular member inserted onto the first

pole and held by the upper lid so as to be rotatable about the first pole;

a first thread provided on an inner face of the first tubular member; and

5 a second thread provided on a surface of the first pole and adapted to engage the first thread.

5. A substrate processing apparatus according to claim 4, wherein the elevator further has:

10 a second pole erected from the upper side of the container so as to extend vertically;

a second tubular member inserted onto the second pole and held by the upper lid so as to be rotatable about the second pole;

15 a third thread provided on an inner face of the second tubular member;

a fourth thread provided on a surface of the second pole and adapted to engage the third thread; and

20 a power transmitting mechanism, disposed between the first and second tubular members, for rotating the second tubular member in synchronization with the first tubular member.

25 6. A substrate processing apparatus according to claim 3, further comprising a tubular cover detachably attached to the first pole so as to cover the surface of the first pole.

7. A substrate processing apparatus according

to claim 1, wherein the chamber has:

a substrate holding part for positioning and holding a substrate; and

5 an electron beam irradiating part for irradiating the substrate with an electron beam.

8. A maintenance method for a substrate processing apparatus having a chamber including a container and an upper lid for closing an upper opening of the container, the method comprising the step of:

10 vertically raising the upper lid and carrying out maintenance within the container while the upper lid is held at a position separated by a predetermined distance from above the container.